

## PATENT APPLICATION

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FORM PTO-1449	ATTY. DKT NO.	1-99	SER. NO.
	APPLICANT	MATSUI	
	FILING DATE	Nov. 13, 2000	GROUP

JC813-109454  
 09/709454  
 11/13/00

## REFERENCE DESIGNATION

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
<i>JB</i>		5,750,434	May 12, 1998	Urushidani et al.	—	—
<i>JB</i>		5,800,577	Sept. 1, 1998	Kido	—	—

## FOREIGN PATENT DOCUMENTS

## TRANSLATION

		DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO
<i>JB</i>		7-80770 (cited in spec. p. 4)	3/95	JAPAN	—	—	—	—	—
<i>JB</i>		56-23746 (cited in spec. p. 5)	6/81	JAPAN	—	—	—	—	—
<i>JB</i>		7-288243	10/95	JAPAN	—	—	—	X ABSTRACT only	
<i>JB</i>		8-22503	3/96	JAPAN	—	—	—	X ABSTRACT	
<i>JB</i>		664540	12/94	EPO	—	—	—	—	—

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

<i>JB</i>	Kikuchi et al., "Mechanochemical Polishing of Silicon Carbide Single Crystal with Chromium(III) Oxide Abrasive", <u>J. Am. Ceram. Soc.</u> , 75 [1], pp. 189-94 (1992) (Note: This article is discussed at page 4 of the specification).
EXAMINER <i>Judi Brinkman</i>	DATE CONSIDERED 10/31/01

Rev. 10/94 (Form 3.05)